



**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Naomasa SHIRAISHI

Group Art Unit: 2851

Application No.: 10/679,151

Examiner: A. MATHEWS

Filed: October 6, 2003

Docket No.: 032136.09

For: PROJECTION EXPOSURE METHOD WITH LUMINOUS FLUX DISTRIBUTION

**AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the May 22, 2006 Office Action, the shortened statutory period for reply being extended by the attached Petition for Extension of Time, please consider the following:

**Amendments to the Specification;**

**Amendments to the Claims** as reflected in the listing of claims; and

**Remarks.**